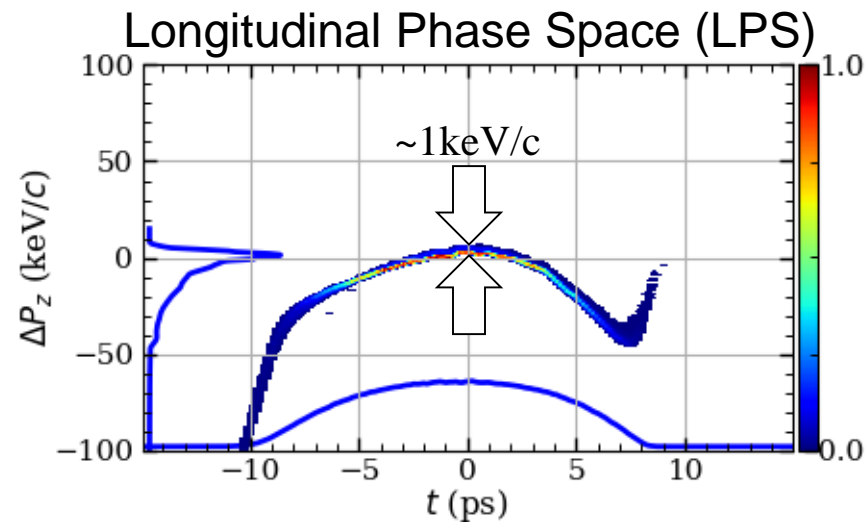


# Slice energy spread measurement at PITZ

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MT ARD ST3 Meeting 2021, 30.09.2021



→ Critical parameter in FEL optimization

**SASE FEL:**

- $\frac{\sigma_E}{E} < \rho_{FEL}$  (e.g.  $1e-4$ , 5 kA/1.4 MeV  $\rightarrow$  20 A/5.6 keV)
- If  $\sigma_E$  too low  $\rightarrow$  microbunching instability (MBI)  
 $\rightarrow$  Laser heater (LH) to suppress MBI (e.g. LCLS  $\rightarrow$  20 keV by LH)

**Seeded FEL:**

Bunching factor and harmonic number

e.g. HGHG@ FERMI: 100 keV  $\rightarrow$  40 keV  $\rightarrow$  16 nm ( $n=15$ )  $\rightarrow$  10 nm ( $n=25$ )

# Slice energy spread measurements

Method = Transverse Deflecting System (TDS) + Dipole

$$\sigma_M^2 = \sigma_{scr}^2 + \sigma_{emit}^2 + \left(D \frac{\sigma_E}{E}\right)^2 + \left(D \frac{\sigma_{E,TDS}}{E}\right)^2$$

	SwissFEL	EuXFEL	Unit
<b>Q</b>	200	250	pC
<b>Ek</b>	100-400	130	MeV
<b>I<sub>peak</sub></b>	20	20	A
<b>dE</b>	15	6	keV
<b>I<sub>peak</sub>/dE</b>	<b>1.3</b>	<b>3.3</b>	A/keV

Why is the energy spread results so different?

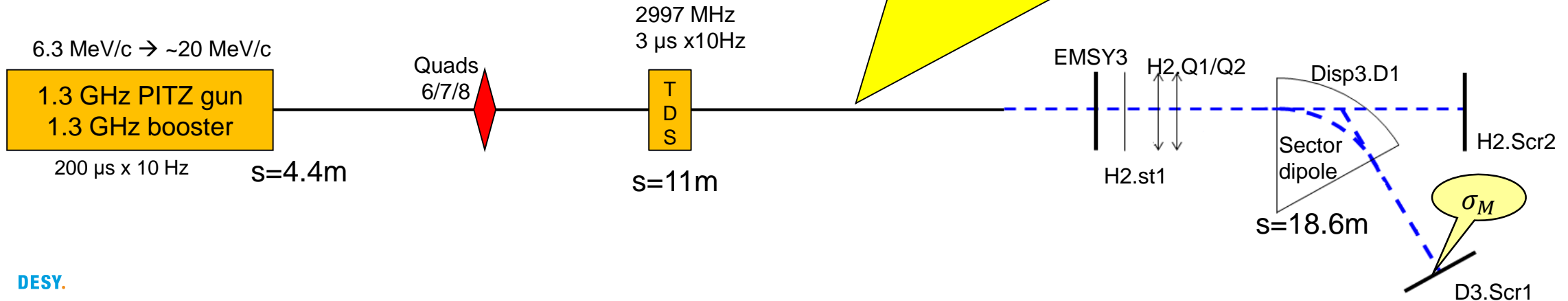
- Cathode effect (Cu vs Cs<sub>2</sub>Te) due to response time
- Laser temporal noise
- Lattice, IBS
- Or measurement effects?

SwissFEL and EuXFEL:

- use **energy scan** or **dispersion scan** to fit contribution from screen and emittance
- require a **constant** central slice  $\beta$  function at dipole screen during scan
- fits better **high** beam energies

Method used at **PITZ**:

- does not require constant  $\beta$  function
- **scan** TDS voltage, then measure  $\sigma_{scr}^2 + \sigma_{emit}^2$  independently with a **slit mask** by scanning R12
- fits better **low energy** injector (closer to electron source)

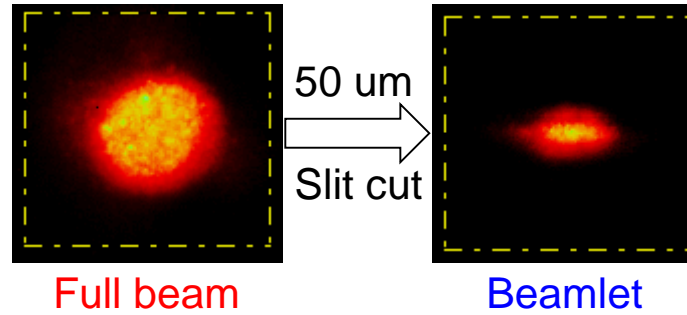
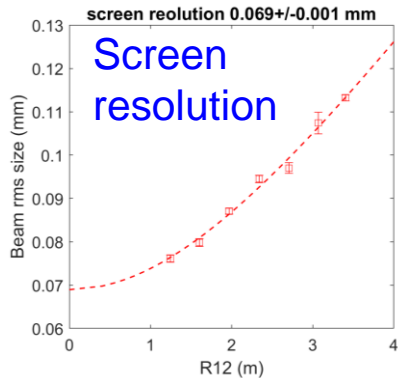


# Slice energy spread measurements at PITZ

## TDS voltage scan with and without vertical emittance reduction

Slits were used to:

- cut emittance to improve TDS time and energy resolution:
  - $\varepsilon_y \sim 0.4 \text{ mm mrad} \rightarrow 0.04 \text{ mm mrad}$
  - a factor of  $\sim 10$  improvement on LPS resolution, reduces the error bar

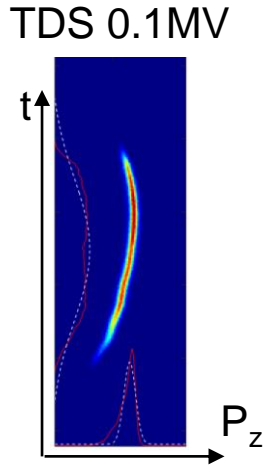
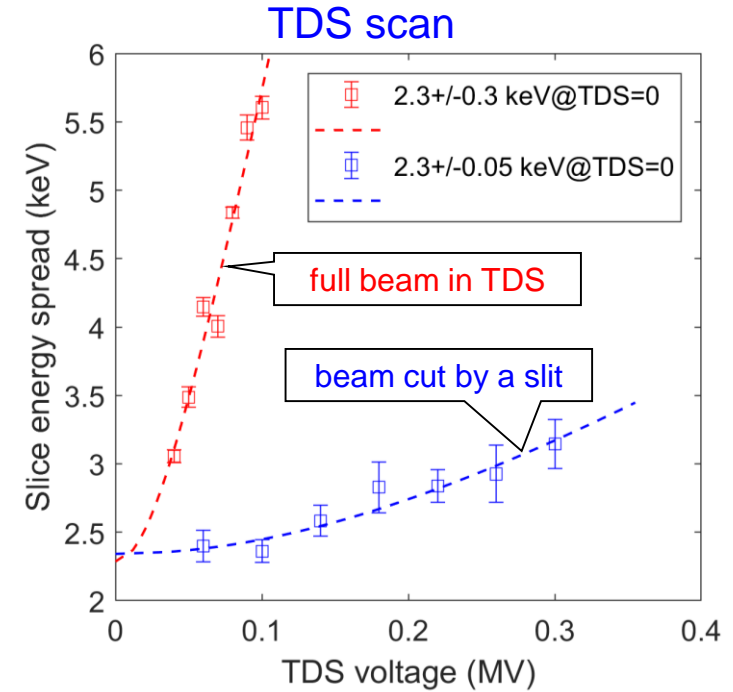


- measure dispersion screen resolution
- measure beam size @dispersion screen due to emittance

$$\sigma_M^2 - \left(D \frac{\sigma_{E,TDS}}{E}\right)^2 = \sigma_{scr}^2 + \sigma_{emit}^2 + \left(D \frac{\sigma_E}{E}\right)^2$$

Total	$\sigma_M = 107 \mu\text{m}$	$\rightarrow 2.33 \text{ keV}$
screen resolution	$\sigma_{scr} = 70 \mu\text{m}$	$\rightarrow 1.52 \text{ keV}$
beam emittance term	$\sigma_{emit} = 30 \mu\text{m}$	$\rightarrow 0.65 \text{ keV}$
slice energy spread	$\rightarrow 76 \mu\text{m}$	$\sigma_E = (1.65 \pm 0.05) \text{ keV}$

ASTRA Simulation value **1.3 keV**



$\sigma_E(t \sim 0) = 1.65 \pm 0.05 \text{ keV}$  was measured for the XFEL nominal working point, slightly higher than ASTRA simulations 1.3 keV, but much lower than high energy injectors